

# IPR0200

## Plasma Treatment Benchtop unit



The IPR0200 plasma machine is designed to meet most R&D needs as well as industrial plasma cleaning, etching and surface activation applications.

Thanks to a user-friendly software interface via an LCD touch screen, and an optimised design of the vacuum chamber chamber, this reactor stands out among the best available on the market today.

With its RF plasma, the IPR is a versatile cold plasma surface activation machine.

Configurable in terms of pumping capacity and gas lines, it ensures simple, effective implementation, whatever your field of activity.

### TECHNICAL SPECIFICATIONS

Unit dimensions	Width	500 mm
	Height	600 mm
	Depth	600 mm
	Weight	65Kg
Chamber dimensions	Volume	20 L
	Width	250 mm
	Height	250 mm
	Depth	320 mm
Power supply	Tension / Frequency / Power Compliance	230 V / 50Hz / 800W CE marking
Human Machine Interface	Touch screen PLC Password access to parameters Languages available : English and French Process curves display	
Gas supply	1 to 4 gas lines Lines equipped with massflow controllers and solenoid valves	
Pressure measurement	Pirani or capacitive pressure gauge	
Power generator	13,56 MHz Frequency	0 - 450 W
Pump	KF 25 connection Recommended minimum flow rate : 30 m <sup>3</sup> /h	
Options	Loading trays ( 250 x 300 mm) Maintenance kit Second electrode Maintenance and servicing in our premises	
Compatible materials	PE, PP, PC, Silicon, PEX, PMMA, PET, PA, ABS, FPM, FKM, ECTFE etc. <i>Please contact us for other materials.</i>	